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Total No. of Pages : 02

Total No. of Questions : 18

**B.Tech. (ECE) (Sem.-5)**  
**VLSI/ULSI TECHNOLOGY**  
Subject Code : BTEC-905C-18  
M.Code : 78709

Time : 3 Hrs.

Max. Marks : 60

**INSTRUCTIONS TO CANDIDATES :**

1. SECTION-A is COMPULSORY consisting of TEN questions carrying TWO marks each.
2. SECTION-B contains FIVE questions carrying FIVE marks each and students have to attempt any FOUR questions.
3. SECTION-C contains THREE questions carrying TEN marks each and students have to attempt any TWO questions.

**SECTION-A****Write briefly :**

- 1) Define polishing process.
- 2) What are various thin oxide properties?
- 3) Explain dry, HCL dry and wet oxidation.
- 4) Define the term lithography.
- 5) What are various clean room and safety requirements?
- 6) What are the desired properties of metallization for integrated circuits?
- 7) Explain mask generation.
- 8) Enlist RTP techniques.
- 9) Define rapid thermal processing.
- 10) Explain CVD.



**SECTION-B**

- 11) Describe characterization of impurity profiles.
- 12) Explain the various effects of impurities and damage on oxidation rate.
- 13) What are wet chemical etching techniques?
- 14) Explain RIE techniques.
- 15) Explain newer lithography techniques for VLSI/ULSI.

**SECTION-C**

- 16) Explain CVD techniques for deposition of polysilicon.
- 17) Describe various oxidation techniques.
- 18) List possible ways of growing an oxide on a substrate without forming oxidation induced stacking faults.

**NOTE : Disclosure of Identity by writing Mobile No. or Making of passing request on any page of Answer Sheet will lead to UMC against the Student.**

